

MEMS, microfluidics and microfabrication for science and technology

Micromagnetometers, actuators, radiation detectors, viscometers

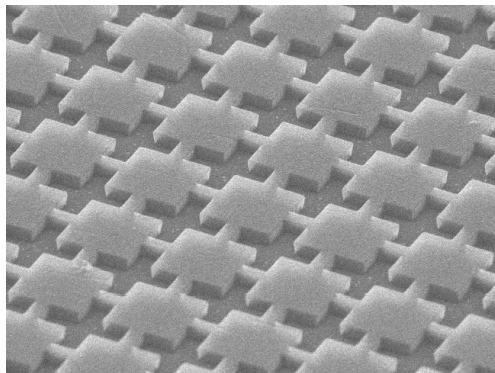
Hernán Pastoriza

Laboratorio de Bajas Temperaturas
Centro Atómico Bariloche & Instituto Balseiro
Bariloche

April 27, 2018

Microfabrication

Lithography



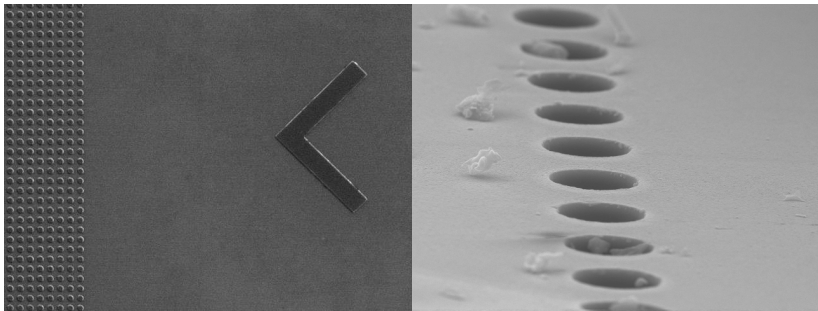
Technique to transfer patterns to flat surfaces.

Limitations: diffraction (light $\lambda \approx 0,3\mu\text{m}$)

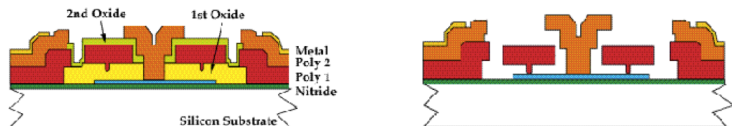
Proximity effect (electrons 15 nm).

Microfabrication

Thin films & etching



How MEMS are done



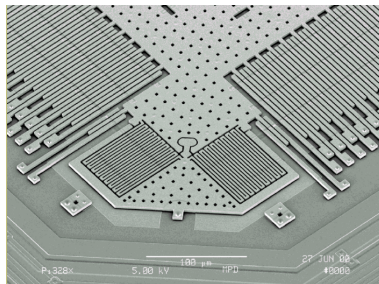
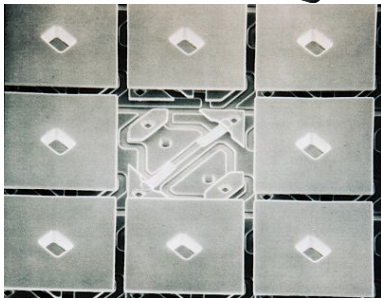
Some chemistry magic...

Layers of different materials (each one patterned separately).

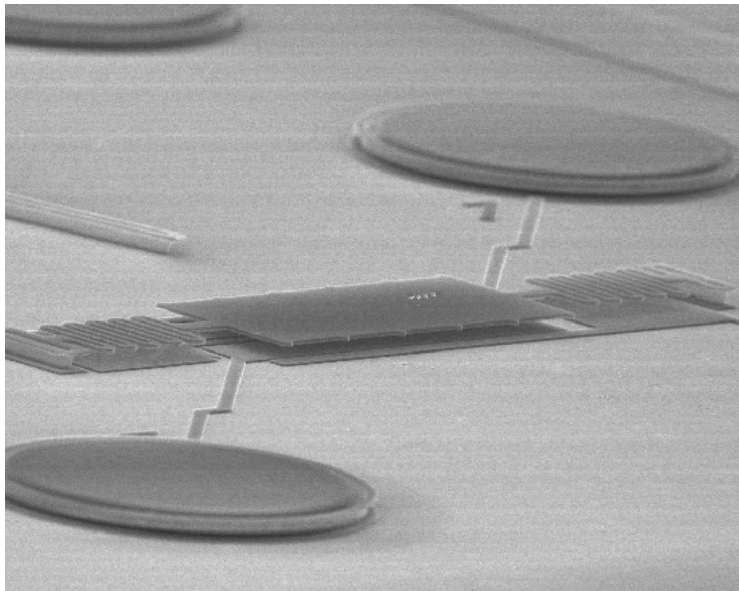
And then a selective etching of one of them.

Result: some parts become released from the underlying layers

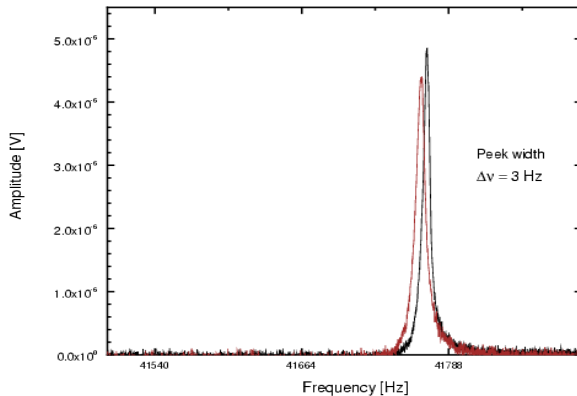
MEMS are everywhere



Torsional Oscillators



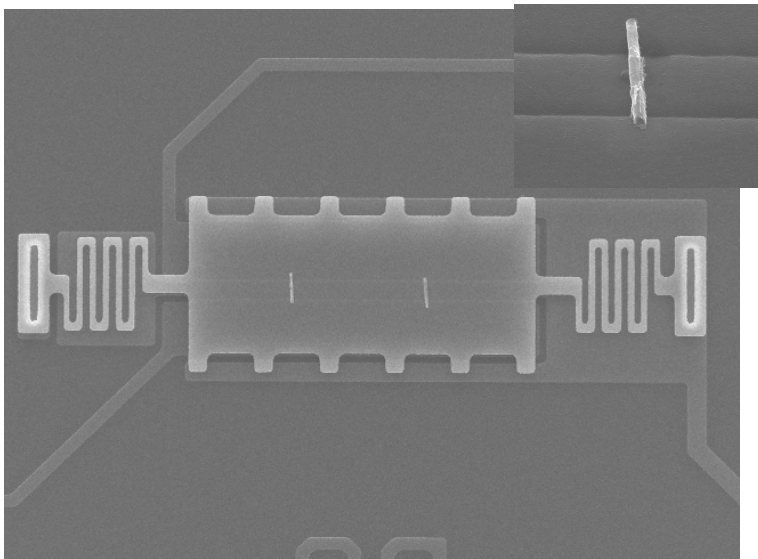
Torsional Oscillators



M. Dolz, D. Antonio & H. Pastoriza, *Physica B* **398** (2007) 329

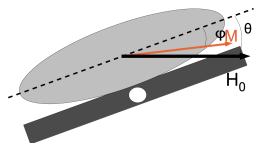
W. Bast, H. Pastoriza & M. Dolz, *Proc EAMTA 2006* (2007) 7–10

Ferromagnetic Nanotubes



Ferromagnetic Nanotubes

$$k = \frac{d^2 E}{d\theta^2}$$



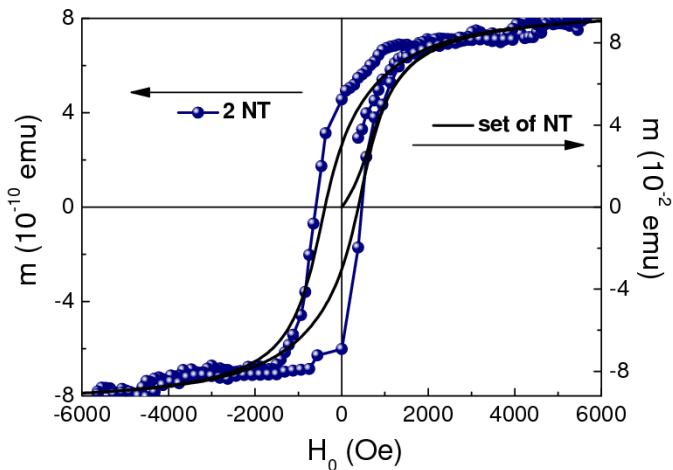
$$E = \frac{1}{2}NM^2(H) \sin^2(\varphi) - M(H)H_0 \cos(\theta)$$

$$\frac{dE}{d\varphi_{\text{eq}}} = 0 \implies \varphi_{\text{eq}} \simeq \frac{H_0}{MN + H_0}$$

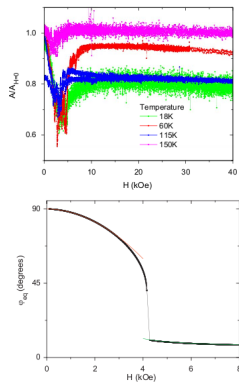
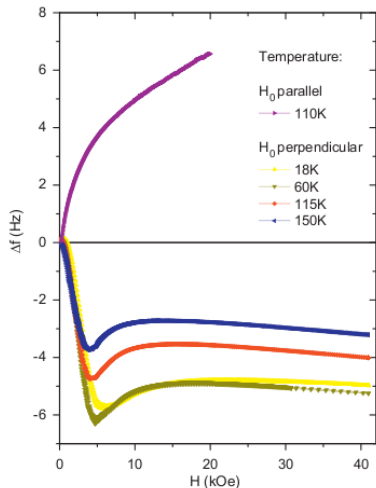
$$\frac{d^2 E}{d\theta^2} = \frac{MNH_0 \left[M(MN + H_0) + \frac{dM}{dH} H_0 (MN + 2H_0) \right]}{(MN + H_0)^2}.$$

At high fields: $-\frac{1}{k} = \frac{1}{MH_0} + \frac{1}{NM^2}$

Ferromagnetic Nanotubes



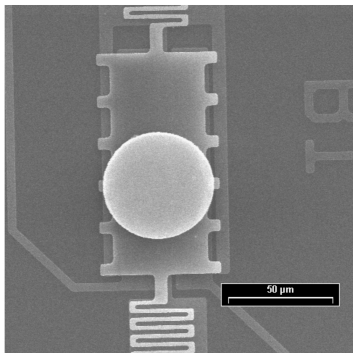
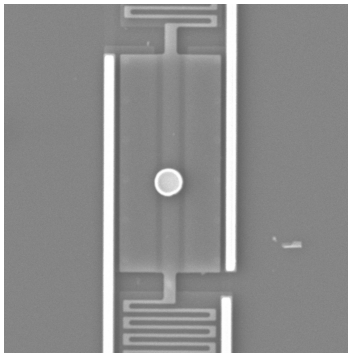
Perpendicular Ferromagnetic Nanotubes



D. Antonio, M.I. Dolz & H. Pastoriza, J. Magn. Magn.

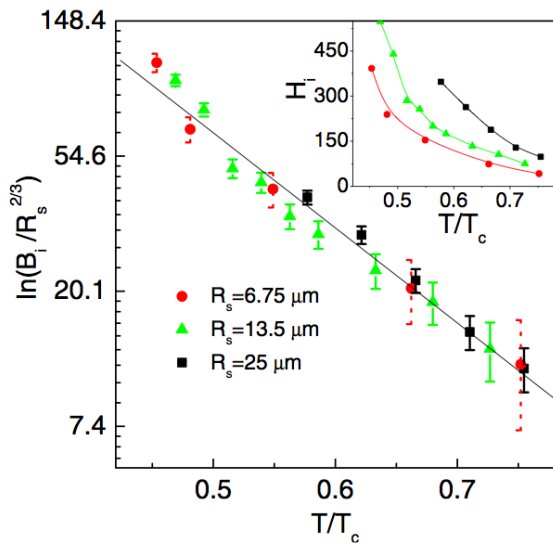
Mater. **322** (2010) 488—493

Measurements in Superconductors

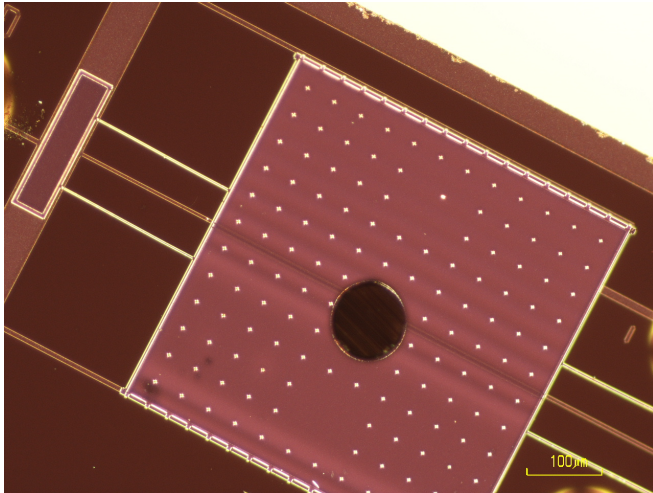


M.I. Dolz, A. K. Kolton, & H. Pastoriza, Phys. Rev. B **81**, 092502 (2010)

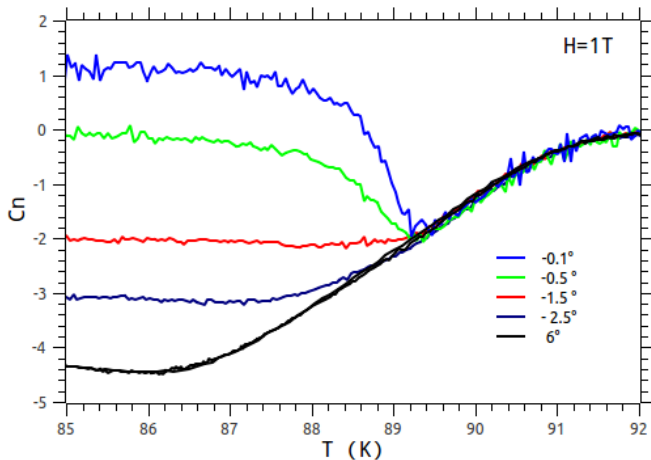
Measurements in Superconductors



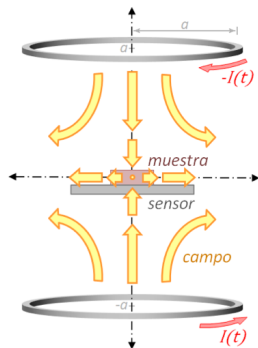
Measurements in Superconductors



Measurements in Superconductors

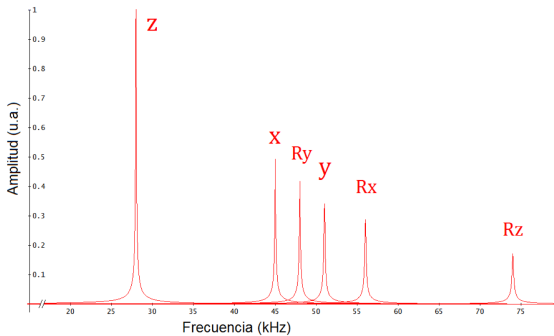
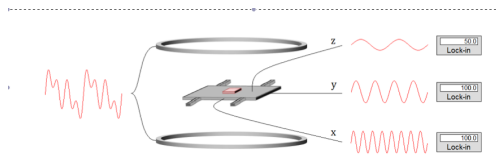


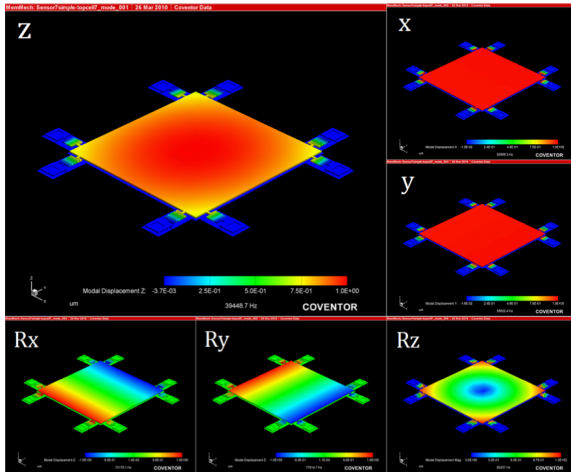
Can the measurement become independent of sample shape?



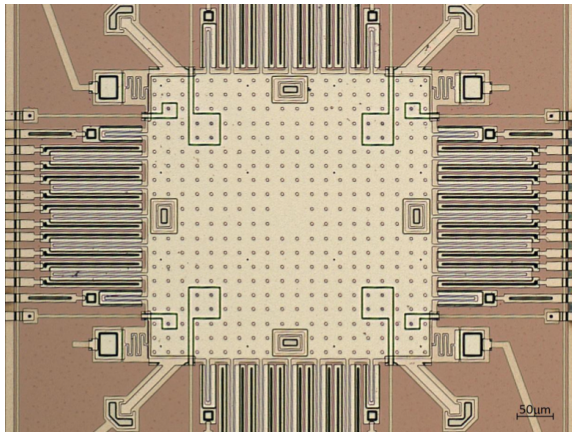
$$\vec{F} = \nabla \vec{H} \cdot \vec{m}$$

microAGM

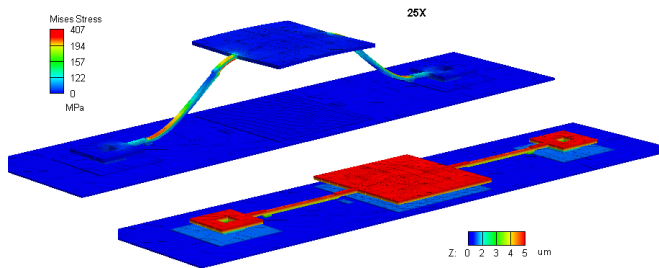




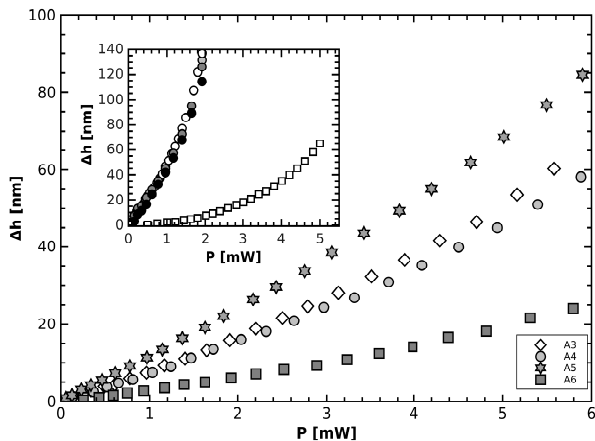
microAGM



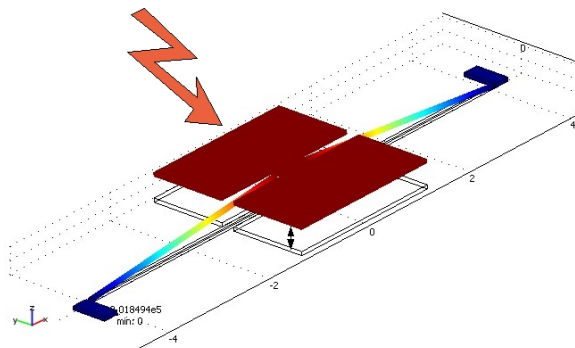
Thermal Actuator



Thermal Actuator



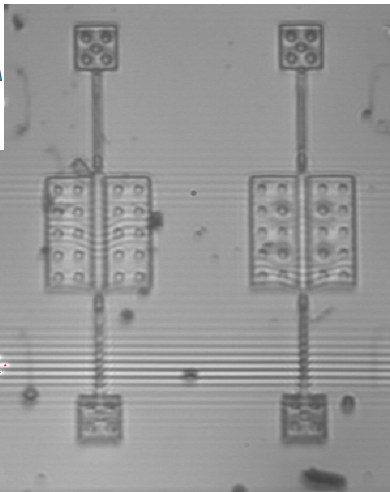
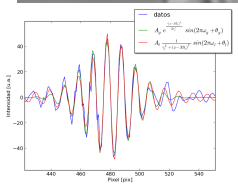
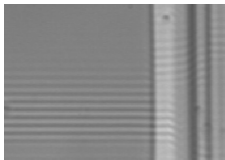
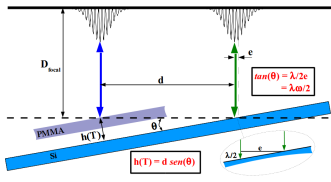
Uncooled Infrared detector



$$\Delta y \approx L\sqrt{2\alpha\Delta T}$$

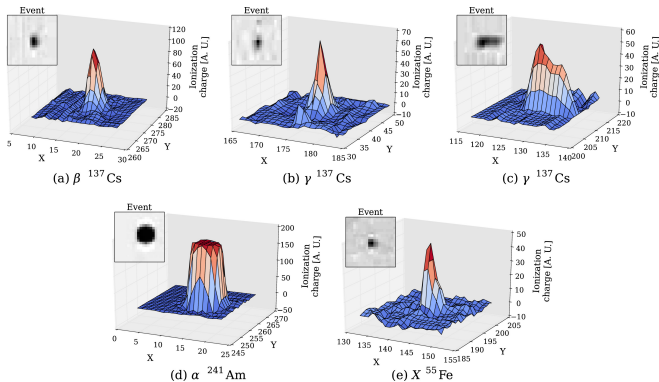
Sensor bolométrico de alta sensibilidad; H. Pastoriza, N. La Forgia, M. Dolz, D. Antonio; Patente Instituto Nacional de Propiedad Intelectual AR 060423B1.

Uncooled Infrared detector



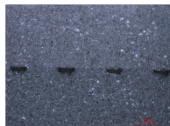
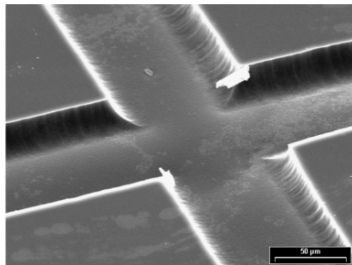
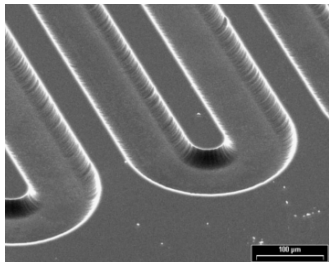
Off the shelf CMOS Image Sensors for Particle Detection

J. Lipovetzky & M. Gómez Berisso

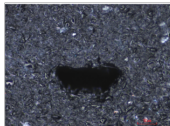


M.Pérez et al. Nuclear Instruments and Methods in Physics Research
Section A: Accelerators, Spectrometers, Detectors and Associated
Equipment, **827** 171, (2016)

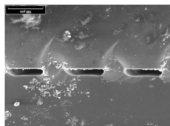
Microviscometer



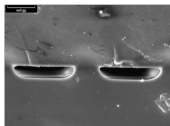
(a) Canal de 50 µm. Escala de 100 µm.



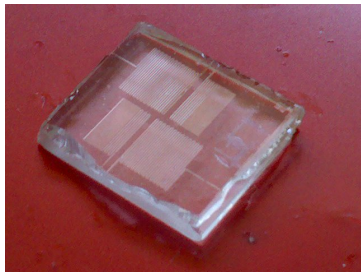
(b) Canal de 50 µm. Escala de 50 µm.



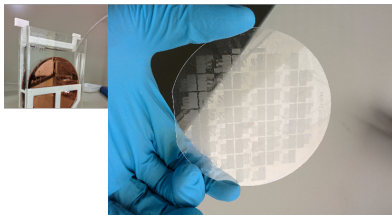
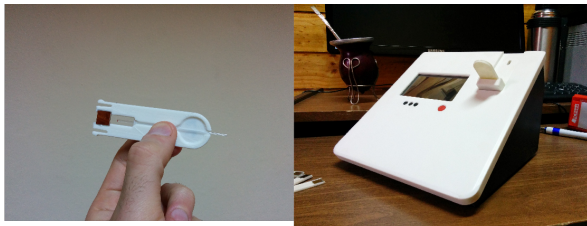
(c) Canal de 100 µm. Escala de 100 µm



(d) Canal de 100 µm. Escala de 50 µm



Prototype



Some Spin-offs and other works¹:

- Cryogenics ASIC-CMOS.
- Magnetometer by using MEMS in non-linear regime.
- Non linearity and synchronization. Frequency lockin
- Devices based in III-V Semiconductors (QWIPs, QCLs, MEMS, Hybrid systems)
- MKIDs
- GEMs
- CMOS Neutron detectors

¹Glad to answer any question

Thanks!